Call for Papers

ICPST-41

The 41st International Conference of Photopolymer Science and Technology

Materials & Processes for Advanced Lithography, Nanotechnology and Phototechnology

June 25 - 28, 2024

International Conference Hall Makuhari Messe, Chiba, Japan

Sponsored by the Society of Photopolymer Science and Technology (SPST)

In Cooperation with
The Technical Association of
Photopolymers, Japan
The Chemical Society of Japan
The Society of Polymer Science, Japan
The Japan Society of Applied Physics, Japan

Introduction

The 41st International Conference of Photopolymer Science and Technology, M aterials & Processes for Advanced Lithography, Nanotechnology and Phototechnology (ICPST-41) organized by SPST will be held at International Conference Hall, Makuhari Messe, Chiba, June 25-28, 2024. The details will appear at the SPST Homepage.

All the contributors of papers on the scientific progress and the technical development of photopolymers are cordially invited.

Scopes

The conference covers a wide range of topics relevant to photopolymer science and technology in the following fields:

A. English Symposia

- A0. Plenary Talk
- A1. Next Generation Lithography, EB Lithography and Nanotechnology
- A2. Nanobiotechnology
- A3. Directed Self Assembly (DSA)
 - →Self-Assembly Materials and Processes (DSA, BCP, SAM, ASD, Infiltration, Nanostructured Materials, Advanced Devices using Self Assembly, etc.)
- A4. Computational / Analytical Approach for Lithography Processes
- A5. EUV Lithography
- A6. Nanoimprint
- A7. 193 nm Lithography Extension
- A8. Photopolymers in 3-D Printing/ Additive Manufacturing
- A9. 2D and Stimuli Responsive Materials for Electronics & Photonics
- A10. Strategies and Materials for Advanced Packaging, Next Generation MEMS, Flexible Devices
- A11. Chemistry for Advanced Photopolymer Science
- A12. Organic and Hybrid Materials for Photovoltaic and Optoelectronic Devices
- A13. Fundamentals and Applications of Biomimetics Materials and Processes
- A14. Polyimides and High Thermally Stable Resins -Functionalization and Practical Applications-
- A15. General Scopes of Photopolymer Science and Technology
- P. Panel Symposium

B. Japanese Symposia

- B1. Polyimides and High Thermally Stable Resins
 -Functionalization and Practical Applications-
- B2. Plasma Photochemistry and Functionalization of Polymer Surfaces
- B3. General Scopes of Photopolymer Science and Technology

Language and Oral Presentation Time

English is used for presentations in English Symposia and Panel Symposium. Japanese and English are used for presentations in Japanese Symposia. Each presentation will not be longer than 20 minutes including discussion except for the notified lectures.

Application to Scientific Program

Apply to [Conference → Presentation-Information Submission] at the SPST Homepage (https://www.spst-photopolymer.org/) before **February 14, 2024**.

Editorial Office

Assoc. Prof. Haruyuki Okamura

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Papers

Papers submitted to ICPST-41 are published in Journal of Photopolymer Science and Technology, Vol. 37 (2024) after reviewing on the Journal's standard. Journal will be distributed to each participant during the conference. Preparation of manuscripts for the Journal should be followed to "Instructions to Authors" and "Manual for Manuscript Writing". Refer "Page Layout Sample" and use "Sample Manuscript (Manuscript Template)". Submit the manuscripts to [Journal → Submission & Reviewing of MS] at the SPST Homepage before **April 1, 2024.** The Journal will be published and mailed before ICPST-41.

Registration for Participants

All the participants including speakers are requested to register in [Conference \rightarrow Registration] at the SPST Homepage.

	By May 31, 2024	From June 1, 2024
Regular Registration	65,000 JPY	80,000 JPY
Student Registration	10,000 JPY	15,000 JPY
Banquet	5,000 JPY	5,000 JPY

X In consideration of the recent rise in prices and ongoing operations, SPST has decided to raise the membership fee.

Conference Office

The 41st International Conference of Photopolymer Science and Technology (ICPST-41)

c/o Prof. Hiroto Kudo

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The Society of Photopolymer Science and Technology (SPST)

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Director of Awards: Itaru Osaka Director of Administration: Hiroto Kudo

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講演募集

ICPST-41

第41回 国際フォトポリマーコンファレンス

リソグラフィー、ナノテクノロジー、 フォトテクノロジー -材料とプロセスの最前線-

2024年6月25日 (火)~28日 (金) 幕張メッセ国際会議場

主催 フォトポリマー学会 (SPST)

協賛 フォトポリマー懇話会、日本化学会、高分子学会 応用物理学会 第41回国際フォトポリマーコンファレンスを下記の要領で開催いたします。 フォトポリマーに関心をお持ちの方々は是非、御参加下さい。

日 時 2024年6月25日(火)~28日(金)

会場 千葉市美浜区中瀬2-1 幕張メッセ国際会議場(JR 海浜幕張下車徒歩5分) 詳細は学会ホームページでご案内します。

講演内容

フォトポリマーに関する科学と技術の研究報告

- A. 英語シンポジウム
 - A0. Plenary Talk
 - A1. Next Generation Lithography, EB Lithography and Nanotechnology
 - A2. Nanobiotechnology
 - A3. Directed Self Assembly (DSA)

 →Self-Assembly Materials and Processes (DSA, BCP, SAM, ASD, Infiltration, Nanostructured Materials, Advanced Devices using Self Assembly, etc.)
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- A15. General Scopes of Photopolymer Science and Technology
- P. Panel Symposium
- B. 日本語シンポジウム
 - B1. ポリイミド及び高温耐熱樹脂-機能化と応用 A14と併設開催(英語発表を希望の場合A14に申し込みをお願いします)
 - B2. プラズマ光化学と高分子表面機能化
 - B3. 一般講演:(1) 光物質化学の基礎(光物理過程、光化学反応など)、(2)光機能素子材料(分子メモリー、情報記録材料、液晶など)、(3)光・レーザー電子線を活用する合成・重合・パターニング、(4)フォトファブリケーション(光成型プロセス、リソグラフィ)、(5)レジスト除去、エッチング、洗浄、(6)装置(光源、照射装置、計測、プロセスなど)

講演時間と言語

原則として討論時間を含め20分。英語シンポジウムは英語、日本語シンポジウムは日本語および英語発表です。

講演申込

学会ホームページ (https://www.spst-photopolymer.org/) [講演募集ICPST-41→日本語会場発表申し込み]からお申し込みください。

講演申込締切

2024年2月14日(水)

論文の出版

ICPST-41の論文はJournal of Photopolymer Science and Technology Vol. 37 (2024) にJournal基準による審査を経て出版されます。 論文原稿は、完全原稿を作成し、2024年4月1日 (月) までに学会ホームページ(https://www.spst-photopolymer.org/)の [Journal→Submission&Reviewing of MS] に投稿してください。

フォトポリマー学会出版局

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参加費

すべての参加者(講演者を含む)は参加費をお支払いください。

	5月31日以前	6月1日以降
一般	65,000 円	80,000 円
学生	10,000 円	15,000 円
懇親会	5,000 円	5,000 円

※昨今の物価高騰および継続的な運営を考慮して、SPSTの会費を値上げすることに致しました。

参加登録方法

講演者を含む全参加者はフォトポリマー学会のホームページ (https://www.spst-photopolymer.org/講演募集icpst-41-2024/参加登録/)より登録ください。

展示会

コンファレンス期間中展示会を併設します。展示会出展企業を募集いたしま す。事務局に申し込みまたはお問い合わせ下さい。

第41回 国際フォトポリマーコンファレンス事務局

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